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APPLIED MATERIALS

2881 Scott Blvd. M/S 2061, Santa Clara, CA 95050

LEGAL DEPARTMENT



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Steven VERHAVERBEKE, et al

Assignee: APPLIED MATERIALS, INC.

Title: METHOD AND APPARATUS FOR WAFER CLEANING

Serial No.: 9/891,849 Confirmation Number Assignment: 4749

Filed: 06/25/2001 Group Art Unit: 1746

Attorney Docket No.: 004711/P01 Examiner: MARKOFF, Alexander

Santa Clara, California
October 17, 2003

RESPONSE TO RESTRICTION REQUIREMENT UNDER 37 C.F.R. 1.143

**Hon. Commissioner of Patents and Trademarks
Washington, D.C. 20231**

Sir:

The present communication is in response to the Office Action dated October 10, 2003, outlining the Examiner's restriction requirement between the following groups:

- I. Claims 1-25, 45, 46, 52-56 and 105-108, drawn to an apparatus, classified in class 134, subclass 184.
- II. Claims 26-44 and 47-50, drawn to a method, classified in class 134, subclass 1.3.

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